

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Steve Biellak, et al.
Title: System and Methods for a Wafer Inspection System Using Multiple Angles and Multiple Wavelength Illumination
Application No.: 09/891,693 Filing Date: June 26, 2001
Examiner: Hoa Q. Pham Group Art Unit: 2877
Docket No.: TNCR.179US0 (M-10693 US) Conf. No.: 1752

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

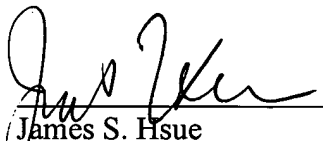
PETITION FOR EXTENSION OF TIME

Dear Sir:

Applicants respectfully petition for a one month extension of time within which to respond to the outstanding Office Action mailed October 19, 2004, such extension allowing the undersigned until February 22, 2005, to respond, February 19, 2005, being a Saturday, and February 21, 2005, being a holiday.

A check is enclosed that includes the amount of \$120.00 , as set forth in the enclosed transmittal letter.

Respectfully submitted,


James S. Hsue
Attorney for Applicants
Reg. No. 29,545

2/22/05
Date

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